

033082M194

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Toshihiro HAYAMI, et al.

CONFIRMATION NO.: 2438

U.S. Serial No.: 10/775,145

Group Art Unit: 1792

Filed: February 11, 2004

Examiner: Maureen Gramaglia

For: PLASMA PROCESSING UNIT AND HIGH-FREQUENCY ELECTRIC POWER
SUPPLYING UNIT

THIRD INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

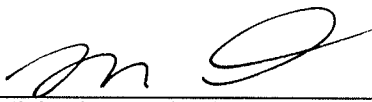
Pursuant to the duty of disclosure under 37 C.F.R. 1.56, Applicants enclose an Information Disclosure Citation Form (PTO-1449) which lists the documents noted in the Japanese Office Action mailed on November 17, 2009 being submitted herewith. A copy of the documents cited therein are enclosed. Documents AA and AF and documents AB and AG are counterparts.

Applicants certify under 37 C.F.R. 1.97(e)(1) that each item of information contained in this Information Disclosure Statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement.

It is respectfully requested that the cited document be considered by the Examiner, that it be made officially of record therein, and that the document be listed on the face of any patent which may issue from this application. An Office Action on the merits has issued for this application. In accordance with the requirements of 37 C.F.R. §1.97(c), Applicants also submit payment of the \$180 requisite fee (37 C.F.R. §1.17(p)).

Respectfully submitted,
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By:



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March 29, 2010